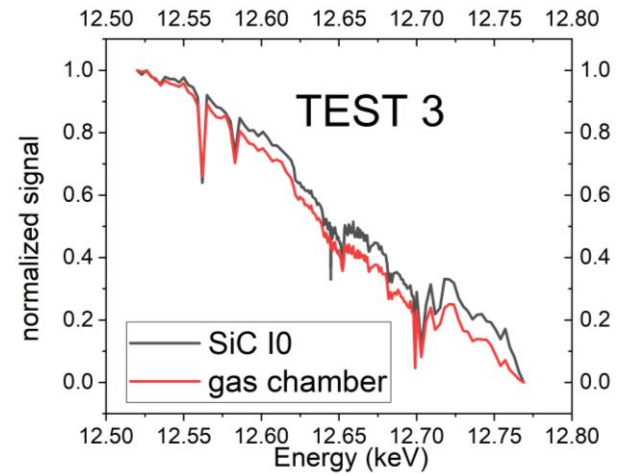
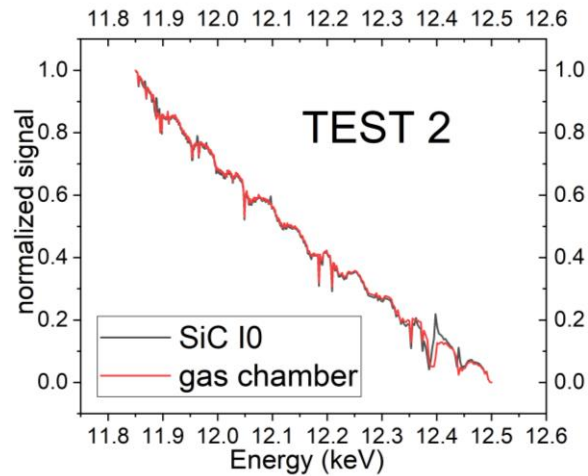
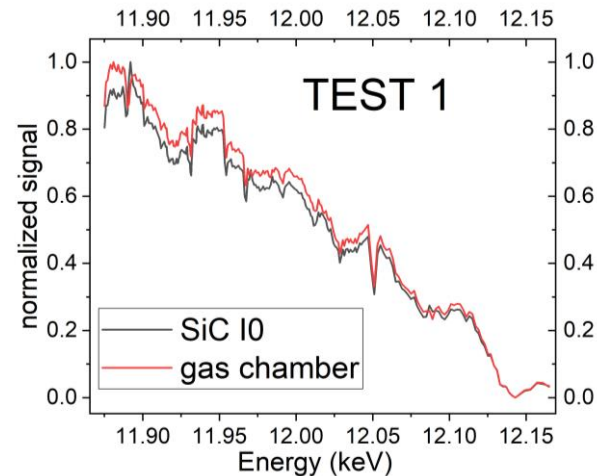
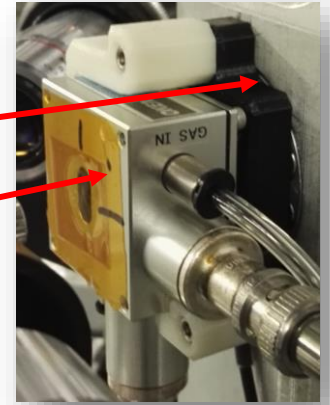


Comparison of 10 μ m Silicon Carbide intensity monitor with gas chamber

10 μ m Silicon Carbide sensor upstream of gas chamber
system thickness (including packaging) <2mm

Gas chamber \approx 4cm thickness



SiC sensor is now used constantly (>1y) as more compact alternative to the gas chamber I0

no diffraction-related glitches have been so far observed